2	Experimental and theoretical investigation of the crystalline
3	surface, film, and interface properties of antiperovskite Mn_3GaN
4	grown by molecular beam epitaxy on $MgO(001)$
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Abstract

We present a study of the epitaxial growth, characterization, and theoretical modeling of thin 31 film antiperovskite Mn₃GaN, an antiferromagnetic material with kagome structure which is grown 32 on MgO (001) substrates using N-plasma-assisted molecular beam epitaxy. Reflection high energy 33 electron diffraction is used to assess the *in-plane* evolution of the film structure during growth, 34 and the surface is investigated *in-situ* using scanning tunneling microscopy and Auger electron 35 spectroscopy. These results are combined with precision measurements done *ex-situ* determining 36 the film lattice constants using a combination of x-ray diffraction with reciprocal space mapping 37 and scanning transmission electron microscopy. Overall, a uniform, homogeneous film with an 38 atomically smooth vacuum surface and atomically sharp substrate interface is found having very 39 small in-plane tensile strain and mild out-of-plane compressive strain. First-principles theoretical 40 calculations are applied in order to ascertain the lowest energy models for both the Mn_3GaN 41 surface and the Mn₃GaN/MgO film/substrate interface. Models including MnGa versus MnN 42 surface layers and MnGa versus MnN interfacial layers are considered as functions of both the 43 Mn and Ga chemical potentials. The predictions are discussed in comparison to the experimental 44 results. The overall findings suggest that Mn_3GaN on MgO(001) is a viable epitaxial film which 45 can be further explored in connection with antiferromagnetic spintronics. 46

47 I. INTRODUCTION

Antiferromagnetic (AFM) materials having non-collinear structures exhibit interesting 48 properties due to their spin configurations. Hexagonal antiferromagnetic compounds like 49 Mn_3Sn [1][2] and Mn_3Ga [3][4] are currently of very high interest. At the same time, these 50 same compounds, when combined with nitrogen, form interesting kagome spin materials hav-51 ing cubic, rather than hexagonal, crystal structures. These are known as antiperovskites, 52 space group Pm3m no. 221. Among the broader antiperovskite family, Mn-based antiper-53 ovskites are a magnetic sub-class having the general formula Mn_3YZ , where Y could be Ga, 54 Zn, Ag, Sn, or some other metallic element. Element Z is a non-metallic element such as C, 55 N, or O which, in the antiperovskite structure, resides at the body center, as compared to 56 the perovskite family in which the non-metallic element usually resides at the face centers 57 [5, 6]. These multifunctional antiperovskite materials exhibit kagome spin structures and 58 magnetic phase transitions. They have been studied for the past few decades using neutron 59 diffraction [5], nuclear magnetic resonance [7], and magnetic susceptibility [8] [9]. Of the 60 general class of Mn-based antiperovskites, the Mn antiperovskite nitride family, including 61 Mn₃GaN, Mn₃ZnN, Mn₃AgN, and Mn₃SnN, is currently gaining a lot of interest. One rea-62 son is the possibility of combining kagome antiferromagnetic materials with wide band gap 63 semiconductors for spintronic applications. 64

 Mn_3GaN has attracted recent interest due to a variety of physical properties, including 65 antiferromagnetism [10], giant barocaloric effect [11], superconductivity [12] and giant mag-66 netoresistance [13]. The Mn spins form a triangular $\Gamma 5g$ kagome-like spin structure, as shown 67 in Fig. 1(a)(b), depicting frustrated antiferromagnetic spin coupling in the kagome lattice 68 plane. In the bulk, Mn₃GaN is known to exhibit antiferromagnetic ordering with a non-69 collinear spin structure in the (111) plane. Thus, it leads to the formation of non-collinear 70 antiferromagnetic (NCAF) spin textures. Below the Neel temperature ($T_N = 298K$), this 71 120° triangular chiral configuration exhibits an anomalous Hall conductivity (AHC) in the 72 (111) Kagome plane [14]. 73

Kim *et al.* studied the molecular beam epitaxial (MBE) growth of GaN and diluted Ga_{1-x}Mn_xN using a single Ga precursor with an Mn solid source. In their experiments, GaN and dilute GaMnN layers were grown on sapphire (0001) and GaAs (001) substrates at various temperatures ranging from 500°C to 800°C. Alongside the main layer growth,

they observed cubic Mn_3GaN as a precipitate [15][16]. Not long after this, Lukashev *et al.* 78 predicted that the magnetic structure of Mn_3GaN could be controlled by applying bi-axial 79 strain [17]. Sunao et al. studied the Mn_3GaN_{1-x} thin films using magnetron sputtering and 80 showed that the deposition rate and the N_2 gas partial pressure could control the tetragonal 81 distortion of the films [18]. More recently, and seemingly consistent with Lukashev *et al.*, 82 Nan et al. reported non-zero unconventional spin torque in a 30-nm Mn₃GaN film grown 83 by DC reactive magnetron sputtering on LaSrAlTaO₃ and inferred that it was due to a 84 tetragonal distortion inducing a small, non-compensated magnetic moment^[19]. Recently, 85 Rimmler et al. reported the growth of Mn_3SnN and Mn_3GaN (25-nm) films by RF-plasma 86 MBE on (001)-oriented MgO substrates, observing the spin Hall effect but attributing it to 87 manganese atomic displacements rather than tetragonal distortion alone^[20]. 88

Due to great interest in the spintronic effects of Mn_3GaN and similar materials (Mn_3SnN 89 for example), it is important to fully characterize the film lattice parameters, including *in*-90 *plane* and *out-of-plane* strains, and the chemical compositions for MBE-grown thin films. 91 Since the origins of important observed effects such as spin Hall effect and anomalous Hall 92 effect are in question, careful characterization studies such as shown here are critical for 93 achieving better understanding in these materials. In this paper, we experimentally explore 94 the detailed structural and chemical properties of Mn_3GaN films grown by MBE on (001)-95 oriented MgO substrates and, in addition, we theoretically investigate the substrate and 96 vacuum interface configurations in the case of Mn_3GaN in order to gain a better under-97 standing of the interfacial bonding and surface structure. 98

99 II. EXPERIMENTAL AND THEORETICAL METHODS

100 A. Experimental

Thin films of Mn_3GaN were deposited on a titanium back-coated MgO (001) substrate using a custom-built MBE system with ultra-high vacuum (UHV) chambers with base pressures of 1.0×10^{-9} Torr and equipped with an N_2 radio frequency (RF) plasma source, Mn and Ga effusion cells, and a quartz crystal sensor for source flux calibration. A STAIB Instruments reflection high-energy electron diffraction (RHEED) system monitors the epitaxial development during crystal formation with a 20 keV incident electron beam. The MgO (001) ¹⁰⁷ substrate was cleaned with acetone and isopropanol before loading into the chamber. The ¹⁰⁸ substrate was annealed at $1000 \pm 50^{\circ}$ C for an hour in a 2.0×10^{-5} Torr N₂ plasma until the ¹⁰⁹ RHEED pattern was streaky along both [100] and [110] directions of the MgO.

To achieve a close to 3:1:1 ratio of Mn:Ga:N, the Mn and Ga flux ratio used was 3.11 110 \pm 0.10. Fluxes were measured by a quartz crystal thickness monitor (QCM). MBE growth 111 was carried out using Mn and Ga fluxes of $\sim 8.70 \times 10^{14}$ atoms/cm²s and $\sim 2.80 \times 10^{14}$ 112 atoms/cm²s, respectively. The RF plasma nitrogen source was operated to give a flux of 113 $\sim 3.50 \times 10^{14}$ atoms/cm²s as determined by the Ga-rich/N-rich crossover point in GaN 114 growth. Given the flux ratios used, we have N-rich growth since, when normalized to N flux 115 $(F_N = 1.00)$, Mn and Ga are 2.49 (< 3) and 0.80 (< 1), respectively. The growth stage 116 temperature was ramped down to $T_S = 250^{\circ}C$ to grow the Mn₃GaN samples. The Mn and 117 Ga shutters were subsequently opened to allow Mn_3GaN sample growth to begin, with a 118 growth rate of 10 nm/min. 119

The reconstructed sample surface is continuously monitored throughout the growth using 120 RHEED. The growth was terminated by closing the Mn and Ga shutters simultaneously 121 and switching off the RF plasma source after 25 min of growth, resulting in a 250 nm thin 122 film, and then slowly ramping down the growth stage temperature using a PID controller. 123 Following the growth process, the sample was transferred *in-situ* to the surface analysis 124 chamber, maintaining vacuum integrity, and allowed to cool to room temperature. The 125 surface analysis chamber has a room-temperature scanning tunneling microscope (RT-STM) 126 system and an Auger electron spectroscopy (AES) system. RT-STM imaging utilized RHK's 127 SPM 100 system in constant-current mode, employing an electrochemically etched tungsten 128 tip for scanning. The surface chemistry of the grown sample was studied by *in-situ* Auger 129 electron spectroscopy (AES). 130

After removing the sample from the vacuum, ex-situ analysis using Bragg-Brentano θ -2 θ 131 X-ray diffraction (XRD) was performed using a Rigaku MiniFlex XRD system with a Cu 132 $K\alpha$ X-ray source of wavelength 1.541 Å. Scanning transmission electron microscopy (STEM) 133 and Energy-dispersive x-ray spectroscopy (EDS) were performed in the Michigan Center for 134 Materials Characterization (MCMC) at the University of Michigan. An *in-situ* FIB lift-out 135 process was utilized for sample preparation, conducted using a Thermo-Fisher Xe plasma G4 136 dual-beam focused ion beam (FIB) system, optimizing beam parameters to 5 keV and 10 pA. 137 Elemental mapping utilized a Thermo-Fisher Talos F200 TEM with four 30 $\rm mm^2$ SSD X-ray 138

¹³⁹ detectors, operating in both STEM and TEM modes. High-resolution imaging employed a
¹⁴⁰ JEOL JEM-3100R05 microscope with double aberration correction, and simultaneous high¹⁴¹ angle annular dark-field (HAADF) and bright-field (BF) imaging were performed in STEM
¹⁴² mode.

143 B. Theoretical

Non-collinear *ab-initio* calculations were performed using the Vienna Ab-initio Simula-144 tion Package (VASP) software [21]. The interactions between core ions and valence electrons 145 were treated within the PAW pseudopotentials scheme [22]. The generalized gradient ap-146 proximation in the Perdew-Burke-Ernzerhof format scheme (GGA-PBE) [23] was applied to 147 describe the exchange-correlation energy. The cutoff radius for the kinetic energy was set 148 to 520 eV. The supercell method was used to model the different interfaces with a space 149 of 15 Å along the Z direction. The interfaces employed six atomic layers for MgO (001) 150 and Mn_3GaN (001) surfaces. Because we employed non-collinear calculations, the spin-orbit 151 coupling breaks the structural symmetries of the MgO (001) surface. The forces on the ions 152 were less than 0.001 eV/Å, and the total energy was converged to 10^{-6} with the Gaussian 153 smearing method. The inversion symmetry was not used in the models. The first Brillouin 154 zone was described by k-point Monkhorst-Pack mesh [24] of $7 \times 7 \times 1$. The calculated MgO 155 lattice constant in bulk was 4.25 Å, which agrees with experimental and theoretical data 156 [25, 26]. We obtained an *a* value of 3.85 Å for Mn₃GaN in bulk, leading to an average error 157 of less than 1.5% compared with experimental results[5]. 158

159 III. RESULTS AND DISCUSSION

¹⁶⁰ A. Growth and Surface Analysis by RHEED

161 1. RHEED Patterns during and after MBE Growth

The evolution of the RHEED patterns during sample growth is shown in Fig. 2. It has eight panels (a-h). The left panel indicates the $[100]_{MgO}$ and the right panel indicates the $[110]_{MgO}$ direction. Fig. 2(a-b) shows the bright streaks along with sharp Kikuchi lines in [100] and [110] directions of the MgO (001) substrate after 1 h of annealing at

1000°C. After opening the shutter, the growth starts and Fig. 2(c-d) shows the RHEED 166 pattern after 25 minutes of growth, while still at the growth temperature of 250 °C. The 167 RHEED pattern looks clear and streaky, but not so sharp, in the zeroth-order Laue rings. 168 Both 1st order and 1/2 order streaks are seen. The broad-width streaks at the growth 169 temperature suggest a certain amount of atomic movement at the surface, with a relatively 170 small coherence length [27]. The sample was cooled down to room temperature, and the RT 171 RHEED patterns appear sharper as shown in Fig. 2(e-f) at the 60 min point (since the start 172 of growth). The sample was maintained at RT until the next day, and the RHEED patterns 173 shown in Figs. 2(g-h) appear very streaky with half-order streaks along [100] appearing 174 clearly. 175

The appearance of sharp half-order streaks, suggesting a 2×1 surface periodicity, was 176 continuously observed. This can be explained by the structure of Mn_3GaN , in which for the 177 (001) MnGa plane, a Mn atom resides at the face center, with Ga atoms at the corners of 178 the conventional unit cell, creating a real-space periodicity doubling for [100] (but not for 179 [010]). It can also be explained from the perspective of the (001) Mn₂N plane in a similar 180 way. Note there is no 1/2-order streak for MgO because of its 1:1 stoichiometry and because 181 the face center atom and corner atoms in any (001) plane are all the same. Similar half-order 182 streaks as for Mn_3GaN were seen by Foley *et al.* and Shrestha *et al.* while growing cubic 183 ϵ -phase Mn₄N [28] and ζ -phase Mn₂N[29]. 184

185 2. Line Profile Analysis of RHEED images

The RHEED line profiles including 1st-order and 1/2-order streaks can be seen in Fig. 3. 186 The *in-plane* lattice spacings along $[100]_{Mn_3GaN}$ and $[110]_{Mn_3GaN}$ directions are determined 187 using line profiles. Line profiles of the MgO substrate along $[100]_{MgO}$ and $[110]_{MgO}$ are shown 188 in Fig. 3(a-b). Line profiles for the Mn₃GaN surfaces along $[100]_{MGN}$ and $[110]_{MGN}$ are 189 shown in Fig. 3(c-h). The less bright and broader-streak line profiles evident in Figs. 3(c-d)190 indicate mobile atom species and/or smaller coherence domain sizes at 250 °C. After cooling 191 down to room-temperature (at the 60-minute mark), 1st-order and 1/2-order peaks become 192 sharper which indicates that the surface lattice periodicity is becoming more coherent. It 193 indicates a more well-ordered surface. Since the film streak symmetries follow from the 194 substrate streak symmetries, we can infer that that the Mn_3GaN film grows epitaxially 195

on MgO (001) with (001) film orientation and crystallograhic orientation relationship is $[100]_{MGN} \parallel [100]_{MgO}$ and $[110]_{MGN} \parallel [110]_{MgO}$, despite an expected lattice mismatch δ of -7.48% defined as $\delta = \frac{a_{Mn_3GaN} - a_{MgO}}{a_{MgO}}$ and where the bulk values used are $a_{MGN} = 3.898$ Å and $a_{MgO} = 4.213$ Å).[5]

Lattice constants are determined from the $[100]_{MGN}$ and $[110]_{MGN}$ line profiles using 200 Lorentzian peak fitting of the 1st-order streaks in order to precisely determine the spacings 201 between peak centroids of the (-1,0) and (+1,0) peaks. Lorentzian peak fitting was also 202 applied to the MgO patterns, also along both [100] and [110], in order to calibrate the 203 RHEED patterns accurately. This method results in highly precise lattice parameters, with 204 relative errors of ± 0.03 % or better for a given line profile. However, more variation was 205 found among different line profiles, and so to take into account profile-to-profile random 206 variations, we took straight averages and standard deviations for the two RT [100] line 207 profiles and for the two RT [110] line profiles separately [see Figs. 3(e,f) and (g,h)], and 208 we find $a_{MGN,[100]} = 3.958 \pm 0.005$ Å along [100] and $a_{MGN,[110]} = 3.936 \pm 0.017$ Å along 209 [110]. The average lattice constant among all 4 line profiles from patterns (e), (f), (g), and 210 (h)] along both [100] and [110] was also taken as a straight average from all these individual 211 values with their standard deviation and found to be 3.947 ± 0.017 Å. These values can be 212 compared to the bulk value (3.898 Å) reported by Bertaut *et al.*[5] 213

214 3. Evaluation of RHEED Streak Widths

The coherence length (or 'domain width') L_c of the surface is inversely related to the 215 half-width Γ of the RHEED streaks via the relation: $L_c = 2\pi/(\Gamma cos(\theta))$, where Γ is in units 216 of inverse Å and θ is the diffraction angle, as discussed by Van Hove *et al.*[30]. Note the 217 Van Hove formula is essentially equivalent to the Scherrer equation if the wave vector k is 218 extracted out of Γ leaving the familiar $D = K\lambda/B\cos(\theta)$, K being the Scherrer constant ~ 219 0.9, λ being the wavelength, and B being the streak angular width in radians. By analyzing 220 the half-widths of the RHEED streaks, we can determine how L_c evolved over the time of 221 the sample growth. To do this, for each primary peak of the RHEED patterns shown in 222 Fig. 3, a straight line (local) background was subtracted, and Γ' was then measured, where 223 Γ' is related to Γ by $\Gamma = \Gamma' - \Delta_{Instr}$ and where Δ_{Instr} is the instrumental broadening. We 224 took an average of the measured Γ' 's from the +1 and -1 streaks for each pattern, and a 225

plot showing the progression of the average Γ' over the growth time t was then created, as shown in Fig. 3(i).

There we can see that the (uncorrected) half-width Γ' began at a total value of 0.35/Å for [100] (0.32 /Å for [110]). After just 25 min of growth, Γ' increased to 0.58/Å ([100] and [110]), corresponding to a decrease in coherence length in the early stage of growth. After 60 min, Γ' reduced to 0.35/Å for [100] (0.43/Å for [110]), indicating an increased surface coherence length. Finally, Γ' came to 0.41/Å for [100] (0.39/Å for [110]) by the next day. (Note: it is unknown why Γ' for [100] at the 60 min point (35 min after stopping the growth) is slightly smaller than the Γ' value after one day).

In order to determine an approximate value for the instrumental broadening, we grew a highly smooth GaN(000 $\overline{1}$) surface in our MBE chamber and extracted an average streak width from the [11 $\overline{2}0$] RHEED pattern (1st order streaks), obtaining a value of 0.235 /Å. This will be an upper limit for Δ_{Instr} . Subtracting this value from the 0.40 /Å for the Mn₃GaN, we get a value for $\Gamma = 0.165$ /Å, corresponding to a value for L_c (or *in-plane* domain width) of 38 Å. This value, although not large, is comparable to about half a terrace width (see STM image section).

242 B. Crystallinity by X-ray Diffraction

243 1. Determination of Lattice Spacing

To understand the crystallinity and orientation of Mn_3GaN thin film, XRD measurements 244 were taken with a Cu K α X-ray source containing both $K_{\alpha 1}$ and $K_{\alpha 2}$ X-rays. Figure 4 shows 245 the XRD spectra for the Mn₃GaN sample as intensity (log scale) vs. 2θ (°). We observe two 246 major peaks and two minor peaks, including a minor 001 peak at 23.08° and a major 002 247 peak at 46.87°, both of Mn_3GaN , with relative intensities of 0.5% and 77.8% of the MgO 002 248 peak, respectively. Finally, a minor peak of Mn_3GaN 111 is seen at 38.57° corresponding 249 to a d-spacing of 4.669 ± 0.011 Å. The major MgO 002 peak is observed at 42.94° , giving 250 a perpendicular d spacing of 2.106 \pm 0.004 Å corresponding to c = 2d = 4.213 Å, in good 251 agreement with the expected lattice constant of MgO[31][32] at 300K. 252

The determined lattice constant LC values from the 001 and 002 XRD peaks of the Mn₃GaN film are 3.855 ± 0.014 Å and 3.878 ± 0.008 Å. The weighted average LC value is 3.872 ± 0.007 Å. Due to the accommodation of lattice mismatch (-7.48%), we can see out-of-plane compressive strain of -1.10 % from the 001 peak and -0.51 % from the 002 peak. A summary of the XRD results is given in Table. I.

²⁵⁸ Non-uniform strain over the film thickness leads to broadening of the $Mn_3GaN 002$ peak ²⁵⁹ with a full-width half maxima (FWHM) of $0.66 \pm 0.10^\circ$, as shown in the zoomed-in inset ²⁶⁰ view of 002 MgO and 002 Mn_3GaN. We can apply Scherrer's equation[33, 34] to determine ²⁶¹ the *out-of-plane* crystallite domain size. Scherrer's equation is:

$$D_{hkl} = \frac{K\lambda}{B_{hkl}cos\theta} \tag{1}$$

and taking the crystallite-shape factor K = 0.9, the XRD wavelength $\lambda = 1.542$ Å, the 002 peak's angular half-width $B_{002} = \frac{1.08^{\circ}}{2} (\frac{\pi}{180^{\circ}}) = 0.005759$ rad, and $\theta = 23.435^{\circ}$, we get D_{002} = 263 Å.

265 2. Reciprocal Lattice Mapping at Off-Axis Angle

The reciprocal spatial map (RSM) around the MgO asymmetric 113 spot plotted in 266 $Q_x - Q_z$ space is illustrated in Fig. 4(b). Both the MgO and the Mn₃GaN elliptical spot are 267 clearly distinguished. The *in-plane* and *out-of-plane* lattice parameters are calculated after 268 precise calibration to the MgO spot in both the x and z directions. The lattice parameters for 269 Mn₃GaN can be determined using equations $Q_x = \frac{\sqrt{h^2 + k^2}}{a}$ and $Q_z = \frac{l}{a}$. The *in-plane* lattice 270 constant, a_{Mn_3GaN} was measured to be 3.850 \pm 0.051 Å. Conversely, the *out-of-plane* lattice 271 constant, c_{Mn_3GaN} , was found to be 3.880 \pm 0.008 Å. The *out-of-plane* -0.46 % (compressive) 272 strain is consistent with the 001 and 002 peak values derived from XRD. Remarkably, the 273 *in-plane* lattice constant from RSM, when compared to the reported 3.898 Å bulk value, 274 corresponds to 1.23 % strain, also compressive; however, the large error bar means that it 275 does not greatly affect the lattice constant weighted averages from our measurements as 276 discussed in the below section. 277

The ideal angle η (for a perfectly cubic structure) shown in Fig. 4(b) equals $\tan^{-1}(\Delta Q_x/\Delta Q_z)$ = $\tan^{-1}(\sqrt{2}/3) = 25.24^{\circ}$, and the measured value for η at midpoint 2 in the figure is 27.40 ± 8.07°. Therefore, the value is in agreement with the expected, but it has a large width (uncertainty).

2θ	Peak label	Plane	Experimental	Reported	Relative Intensity
(degree)		hkl	d value (Å)	d value (Å)	A.U.
23.08°	${\rm Mn_3GaN}$	001	3.855 ± 0.014	3.898	0.05
38.57°	${\rm Mn_3GaN}$	111	2.330 ± 0.011	2.250	0.03
42.94°	MgO	002	2.106 ± 0.004	4.213	1.00
46.87°	${\rm Mn_3GaN}$	002	1.939 ± 0.008	1.949	0.78

TABLE I. Summarized table showing experimental and reported [5][31] d values for different peak positions observed on XRD scan.

282 C. X-Sectional and Lattice imaging from STEM

Atomically resolved bright-field (BF) and high-angle annular dark-field (HAADF) image 283 of Mn_3GaN grown on MgO are shown in Fig. 5(a)(c). Mn_3GaN layer appears to be dark 284 in the BF image and light in the HAADF region. This color contrast is produced by the 285 different charge densities of Mn_3GaN and MgO. The bright-field image captured in Fig. 5(a) 286 provides a detailed depiction of both the substrate and the sample, showcasing a well-defined 287 and organized interface. Noteworthy is the observation of the pseudomorphically strained 288 Mn_3GaN film, matching one-to-one with the MgO substrate lattice at the interface along 289 the yellow dotted line. 290

Figure. 5(b) shows the elemental composition maps of Mn, Ga, and N. The uniform 291 composition across the film indicates highly uniform and crystalline growth. Upon close ex-292 amination of the STEM-HAADF image of Mn_3GaN in Fig. 5(c), a distinct pattern emerges, 293 revealing alternating dark and bright spots corresponding to Ga and Mn atoms in one row, 294 followed by a row solely composed of Mn atoms. Fig. 5(d) shows a zoomed-in view of 295 the dashed red square region seen in Fig. 5(c), overlaid with green and magenta atoms on 296 Mn and Ga atomic sites. This observation verifies the cube-on-cube (001)-oriented crystal 297 alignment of the film, as modeled in Fig. 5(e)[36]. As shown in Fig. 5(f), the Mn₃GaN layer 298 is continuous and flat over large distances as indicated by the wide-view STEM image. 299

We use the HAADF STEM image of the MgO substrate to calibrate the image scale in Fig. 5(c), resulting in a measured value for the *in-plane* spacing of 3.930 ± 0.020 Å, in good agreement with the RHEED value (3.947 ± 0.017 Å) and corresponding to a tensile strain of +0.82 % compared to the expected a = 3.898 Å[5]. The *out-of-plane* spacing is measured at 3.845 ± 0.020 Å, in good agreement with the weighted average XRD value from 001 and 002 peaks (3.872 ± 0.009 Å) and corresponding to a compressive strain of -1.36 %.

D. Summary of Lattice Constants, In-plane and Out-of-plane Strains, and Poisson's Ratio

The results for *in-plane* (transverse) and *out-of-plane* (longitudinal) lattice parameters are summarized in Table II and also in a graphical form in the Supplementary file (Fig. S2). Using these experimental values, together with the measurement uncertainties, we derive a value for the inverse-sigma-squared (quadrature method) weighted average for the *in-plane* LC (a_t) of 3.934 ± 0.013 Å, and for the *out-of-plane* LC (a_l) a value of 3.874 ± 0.005 Å).

To determine strain values, we take as a fixed reference point the published theoretical value for Poisson's ratio from the Materials Database, $\mu = 0.260$. We make the assumption that this value is not greatly dependent on small variations of stoichiometry or small variations of lattice constant, and then we use our measured weighted average a_t and a_l values to determine a new experimental value for a_{MGN} using the formula:

$$\mu_{MGN} = -\epsilon_t / \epsilon_l \tag{2}$$

³¹⁸ which can be expanded and rearranged to give:

$$a_{MGN} = \frac{a_t + \mu \ a_l}{1 + \mu} \tag{3}$$

The resulting value is $a_{MGN} = 3.922 \pm 0.011$ Å, which is very close to the equilibrium lattice parameter in AFM configuration.[37] This determines the strain values for the film (ϵ_t and ϵ_l), and the measured and derived values are all shown in Table II.

We can also calculate the degree of relaxation δ of the film using the derived a_{MGN} value and the following formula:

$$\delta = \frac{a_{MGN,t} - a_{MgO,t}}{a_{MGN} - a_{MgO,t}} \tag{4}$$

which yields $\delta = 95.9 \pm 8.1 \%$ relaxed. Note that $\delta = 0\%$ indicates a film fully strained to its substrate, whereas $\delta = 100\%$ indicates a fully relaxed film[35]. Therefore, to one sigma uncertainty, the result is consistent with a fully *in-plane* relaxed film, consistent with $\epsilon_t =$ 0.31 %.

TABLE II. Summary table showing *in-plane* and *out-of-plane* lattice constants for *in-situ* and *ex-situ* measurements, the weighted average values, the derived experimental lattice constant for Mn_3GaN , and the derived strain values assuming the theoretical value for Poisson's ratio.

Orientation	RHEED	RSM	STEM	XRD	Weighted Ave	Strain
	(Å)	(Å)	(Å)	(Å)	(Å)	(%)
In-plane	3.947 ± 0.017	3.850 ± 0.050	3.930 ± 0.020	-	3.934 ± 0.013	$+0.31 \pm 0.34$
Out-of-plane	-	3.880 ± 0.008	3.845 ± 0.020	3.872 ± 0.007	3.874 ± 0.005	-1.22 ± 0.13

Experimental value for $a_{MGN} = 3.922 \pm 0.011$ Å

Theoretical Poisson's ratio = 0.260

E. Elemental Mapping from STEM - Energy Dispersive Spectroscopy

Fig. 6(a) shows the EDS elemental mapping of the film and the substrate including at 329 the interface and also at the surface. EDS line profiles are taken near the interface. The 330 average elemental compositions near the interface (see Supplemental) are measured to be 331 (Mn) 34.8 ± 3.4 atomic %, (Ga) 12.4 ± 2.4 atomic % and (N) 2.0 ± 1.4 atomic %. Shown 332 in Fig. 6(b) are plots of the stoichiometric ratios Mn:Ga, N:Ga and Mg:O as a function of 333 position along the interface in nm. These ratios are depicted with grey, red, and blue color 334 profiles, respectively. The averaged Mn:Ga, N:Ga and Mg:O ratios are calculated to be 2.81 335 \pm 0.79, 0.16 \pm 0.14, and 1.21 \pm 0.34 respectively. Note the large amount of uncertainty 336 owing to a large amount of fluctuation in the data values from this measurement. Even the 337 Mg:O ratio (1.21 ± 0.34) shows a large fluctuation but easily agrees with a 1:1 Mg:O ratio. 338

The Mn:Ga ratio (2.79 ± 0.79) average matches 3:1 easily within the fluctuations of the data. This data suggests a very small N:Ga ratio (0.16 ± 0.14) , but it is well known that EDS is not very sensitive to N and lighter elements, so this N:Ga value is not reliable.

342 F. Surface Chemical Composition from AES

343 1. Gallium to Manganese and Gallium to Nitrogen Ratios

The stoichiometry of the upmost surface layers of the sample grown with a Mn:Ga flux ratio of 3.11:1.00 was determined using *in-situ* Auger electron spectroscopy by acquiring AES spectra with an incident electron beam of 5.000 keV. From the AES measurements, the ratios of Mn:Ga and N:Ga are calculated based on the following equations:

$$Mn: Ga = \frac{(I_{Mn}^{pp}/S_{Mn})}{(I_{Ga}^{pp}/S_{Ga})} = (\frac{I_{Mn}^{pp}}{I_{Ga}^{pp}})(\frac{S_{Ga}}{S_{Mn}})$$
(5)

$$N: Ga = \frac{(I_N^{pp}/S_N)}{(I_{Ga}^{pp}/S_{Ga})} = (\frac{I_N^{pp}}{I_{Ga}^{pp}})(\frac{S_{Ga}}{S_N})$$
(6)

$$N: Mn = \frac{(I_N^{pp}/S_N)}{(I_{Mn}^{pp}/S_{Mn})} = (\frac{I_N^{pp}}{I_{Mn}^{pp}})(\frac{S_{Mn}}{S_N})$$
(7)

where I_{Mn}^{pp} , I_{Ga}^{pp} , I_N^{pp} are the peak-to-peak intensities of the dN(E)/dE versus E curves for Mn, Ga and N, respectively, and where $S_{Mn_{592}}$, $S_{Ga_{1069}}$ and $S_{N_{389}}$ represent the sensitivity factors of Mn, Ga, and N, respectively (measured in our AES system using calibration samples). Fig. 6(c) shows the AES spectra taken at the three different positions of the sample. The results for the averages from three spots on the sample surface are given in Table III.

Here, the measured Mn:Ga ratio is within ~ 4.3% of the ideal 3:1 Mn:Ga ratio (for Mn₃GaN) and only 0.74 % larger than the incident Mn:Ga flux ratio (3.11); whereas, the measured N:Ga ratio is 72% larger than the ideal 1:1 ratio (for Mn₃GaN) but only 38 % larger than the incident N:Ga flux ratio (1.25); and finally, the measured N:Mn ratio is 67% larger than the ideal 0.33 (for Mn₃GaN) but only 37 % larger than the incident N:Mn flux ratio (0.40), both indicating a N-rich surface. It is important to note that the surface composition can be influenced by the high efficiency, radio-frequency N plasma source used during the growth

Element	P-P Intensity (A.U.)	Measured Sensitivity Factor	Concentration Ratio
Mn	41030 ± 2556	1.15	-
Ga	8540 ± 1123	0.75	-
Ν	40865 ± 921	2.09	-
Mn:Ga	-	-	3.13 ± 0.61
N:Ga	-	-	1.72 ± 0.26
N:Mn	-	-	0.55 ± 0.05

TABLE III. Auger Spectroscopy Data Tabulated

and the precise order in which the Mn, Ga, and N fluxes were terminated. Another unknown
factor is the sticking coefficient of N in comparison to that for Ga or for Mn on the Mn₃GaN
surface.

264 2. Oxygen Adsorption at the Surface

We also notice an AES peak at the energy range 510-512 eV which consists of a combina-365 tion of O_{510} and Mn_{512} . Using the known peak-to-peak intensity ratio (from book spectra) 366 of Mn_{512} to Mn_{592} , we can extract the oxygen signal from the O+Mn peak complex. Details 367 are given in Supplementary note 1. The results indicate a surface O/Mn ratio of 7.84 %, and 368 using the results (shown in the following) for the theoretical lowest energy surface structure 369 being Mn+Ga (1:1 ratio in the top layer), we find the surface O/(Mn+Ga) fraction = 3.92 370 %. Surface oxygen is most likely coming from chamber background gases, possibly from the 371 AES filament. 372

373 G. Surface Morphology by STM

To examine the Mn₃GaN surface structure, *in-situ* STM was performed at room temperature by transferring the sample from the MBE system through a gate valve directly into the adjoining STM chamber. Fig. 7(a) shows an image of size 207 Å \times 207 Å, consist-

ing of multiple terraces separated by bilayer height steps. Terrace 4 appears to contain a 377 threading dislocation, as suggested by the variable height step emerging out of the terrace. 378 A line profile cutting across terraces 2, 3, and 4 is shown in Fig. 7(b). This profile shows 379 step heights measuring 3.81 ± 0.05 Å, in good agreement with $2d = a_{Mn3GaN} = 3.863$ Å, 380 the compressively-strained *out-of-plane* lattice constant a_l based on the weighted average 381 of RSM, XRD, and STEM results. The 2-ML-height steps are better illustrated in the 382 3D perspective view shown in Fig. 7(c) and suggest that only one of the two inequivalent 383 atomic layers is stable at the surface. Theoretical calculations (see next section) explore the 384 question of which atomic layer is more stable - the MnGa layer or the Mn_2N layer. 385

There is some visible substructure within the terraces on a length scale of 1-2 nm which may indicate some surface disorder, possibly caused by nitridation, which may have occurred at the end of growth. That would be consistent with the N/Ga ratio measured by *in-situ* AES (1.72 ± 0.26) suggesting a N-rich surface and the finding (see theory section) that the Mn₂N surface is unstable.

391 H. Theoretical calculations

We performed first-principles calculations to study the first stages of epitaxial growth and the atomic structure at the substrate interface and at the vacuum surface of the Mn_3GaN film grown on MgO(001).

³⁹⁵ 1. High Symmetry Adsorption Sites on MgO(001) Surface

First, to precisely understand the initial stages of growth, we have considered the adsorption of full monolayers of Mn, Ga, and N at different high symmetry sites. These sites are illustrated in Fig. 8(a). For instance, at the Top-O site, the atom is placed on the first O layer. The adsorption at Top-Mg occurs when the atom is deposited on the first Mg layer. The bridge site is reached when the atom is added between the Mg and O atoms of the first layer. For hollow sites, the atom is placed in the hollow site of the unit cell, as seen in Fig. 8(a).

Relative energies $E - E_0$ for each adsorbed atom on different high symmetry sites are calculated to determine the most stable configuration in each case, where E and E_0 are the total energy of the given configuration and the total energy of the lowest energy configuration
for a given adsorbed atom, respectively. The results are listed in table IV, demonstrating
that the Top-O site is the most stable configuration for all elements.

Site	Mn	Ga	Ν
Top-O	0.00	0.00	0.00
Top-Mg	2.28	0.88	9.2
Hollow	1.13	9.9	0.14
Bridge	1.87	0.68	7.8

TABLE IV. Relative energies (eV) for Mn, Ga, and N adsorption at different high symmetry sites.

408 2. Adsorption Energies at Top-O Site

To define the most stable configuration among Mn, Ga, and N adsorption at Top-O site, the adsorption energy was calculated (E_{ads}) from the following equation [38]:

$$E_{ads} = E_{x/MgO} - E_{MgO} - E_x \tag{8}$$

where $E_{x/MgO}$ is the total energy of the surface with the adsorption of x = Mn, Ga and N. E_{MgO} signifies the total energy of the clean MgO (001) surface, and E_x is the total energy of an isolated atom, which is modeled by placing an atom into a unit cell of 20 Å × 20 Å \times 20 Å to avoid the periodic interactions. Spin-polarized calculations were employed for all elements. A negative value suggests thermo-positive and favorable adsorption.

Table V lists a summary of the adsorption energies for the Top-O site. The energies reveal that the Ga adsorption is the most stable configuration, this is partially attributed to the formation of covalent bonds. On the other hand, the N adsorption is unstable on the MgO (001) surface. Therefore, Ga adsorption was carefully considered while studying interface formation energies, and subsequently, we built different models based on Ga adsorption to explain the experimental results.

Element	E_{ads}
Mn	-2.17
Ga	-4.21
Ν	0.82

TABLE V. Adsorption energies (eV) for Mn, Ga, and N adsorption at Top-O site.

422 3. Interface Structure Optimization

The optimized structures of four different interfaces are shown in Fig. 8(b-e), and the 423 interfacial configurations are described as follows: Fig. 8(b) represents model 1, which has 424 a Mn_2N layer as the initial layer of Mn_3GaN and an interlayer distance at the interface of 425 3.39 Å. Model 2 consists of an interface between MgO and MnN, as seen in Fig. 8(c), with 426 a bond length of 2.82 Å and 2.15 Å for N-O and Mn-O, respectively. Model 3 as shown in 427 Fig. 8(d) consists of an interface configuration between MgO and a full Ga monolayer with 428 a bond length of 2.78 Å. Finally, model 4 consists of an interface between MgO and MnGa, 429 as shown in Fig. 8(e), and having an interplanar distance of 2.14 Å. 430

To determine the most stable interface, the interface formation energy (IFE) formalism was employed by applying the following definition [39]:

$$IFE = \frac{E_{Interface} - E_{MgO} - E_{Mn_3GaN}}{A_{interface}} + \sigma_{MgO} + \sigma_{Mn_3GaN} \tag{9}$$

where $A_{interface}$ is the interface area, $E_{interface}$ is the total energy of a fully relaxed interface structure, and where E_{MgO} and E_{Mn_3GaN} correspond to the total energy of the isolated MgO slab and isolated Mn₃GaN slab, respectively.

In Eq. (9), σ_{MgO} is the surface formation energy of the MgO surface, which is defined as:

$$\sigma_{MgO} = \frac{1}{2A} \left[E_{MgO}^{slab} - \frac{1}{2} (n_{Mg} + n_O) \mu_{MgO}^{bulk} - \frac{1}{2} (n_{Mg} - n_O) (\mu_{Mg} - \mu_O) \right]$$
(10)

where A is the area of the MgO surface, E_{MgO}^{slab} corresponds to the total energy of the MgO surface, and where n_i and μ_i are the number of atoms and the chemical potential of the ith species, respectively. The chemical potentials have been varied from Mg-rich conditions $(\mu_{Mg} = \mu_{Mg}^{bulk})$ to Mg-poor conditions $(\mu_{Mg} = \mu_{Mg}^{bulk} - \mu_{O_2}^{mol})$. Because we have employed the ideal MgO (001) surface, i.e. no vacancies, the surface formation energy is the same for both conditions, which has a value of $\sigma_{MgO} = 0.1 \text{ eV}/[1 \times 1 \text{ cell}].$

The interface formation energies of all models were computed and are displayed in Fig. 443 9(f) as a function of Mn and Ga chemical potentials (see the Supplementary file for 2-444 D graphs of this information). It is seen that both model-1 (blue) and model-2 (mauve) 445 interfaces are unstable along all Ga and Mn chemical potentials. The MnN and Mn₂N 446 interfaces are unstable due to the formation of covalent bonds between N and O, as discussed 447 in the adsorption study. Model-3 (green), consisting of a Ga atomic layer, represents the 448 most stable interface under Ga-rich conditions for the whole range of Mn chemical potential. 449 Nonetheless, Ga-rich conditions were most likely not reached in the experiment. On the other 450 hand, model-4 (red), consisting of a MnGa atomic layer, is stable for Ga-poor conditions for 451 both Mn-rich and Mn-poor conditions. This is consistent with the experimental conditions. 452 We can conclude that the most favorable interface under the observed experimental (Mn-453 rich) conditions is formed by MnGa on MgO. This result differs from the previous work by 454 Quintela *et al.* |6| who found a stable interface between Mn₂N and AlO₂. Both results reveal 455 the important role played by the substrate in determining the film/ substrate interface. 456

457 4. Lowest Energy Surface Model

The surface formation energy of the Mn₃GaN surface is represented by σ_{Mn_3GaN} , and since Mn₃GaN is a ternary compound, and since the Mn and Ga fluxes were regulated by experimental conditions, the surface formation energy can be written in the following form, as has been applied in other ternary systems [40–42]:

$$\sigma_{Mn_3GaN} = \phi - \frac{1}{A} [(n_{Mn} - 3n_N)\Delta\mu_{Mn} - (n_{Ga} - n_N)\Delta\mu_{Ga}]$$
(11)

462 with

$$\phi = \frac{1}{A} \left[E_{Mn_3GaN}^{slab} - n_N E_{Mn_3GaN}^{bulk} - (n_{Mn} - 3n_N) E_{Mn}^{bulk} - (n_{Ga} - n_N) E_{Ga}^{bulk} \right]$$
(12)

where $E_{Mn_3GaN}^{slab}$ is the total energy of each Mn₃GaN slab, $E_{Mn_3GaN}^{bulk}$ is the total energy of Mn₃GaN in bulk, E_i^{bulk} is the total energy of Mn and Ga in bulk, and $\Delta \mu_{Mn}$ and $\Delta \mu_{Ga}$ are the variations of the Mn and Ga chemical potentials, respectively. The E_{Mn}^{bulk} , E_{Ga}^{bulk} , $E_{N_2}^{mol}$ and $E_{Mn_3GaN}^{bulk}$ energies have been calculated by modeling a) the α -Mn bulk phase with 58 atoms per unit cell; b) the Ga bulk phase in its normal crystalline unit cell; c) the isolated N₂ molecule in a cube of 20 Å × 20 Å × 20 Å; and d) the ternary Mn₃GaN alloy in its antiperovskite structure unit cell. In a similar way, the chemical potentials μ_{Mg} and μ_{O_2} have been obtained by modeling Mg in its hexagonal unit cell and O₂ with an isolated O₂ molecule in a cube of 20 Å × 20 Å × 20 Å.

Regarding the variations of the chemical potentials, the individual chemical potential of each atomic species (Mn, Ga, N) must be less than the corresponding values for the pure bulk of the same atomic species. Otherwise, these atoms would precipitate into their elemental forms out of the Mn₃GaN material. Therefore, the upper boundary conditions for the variations of the chemical potentials can be written as:

$$\Delta \mu_{Mn} = \mu_{Mn} - E_{Mn}^{bulk} < 0 \tag{13}$$

$$\Delta \mu_{Ga} = \mu_{Ga} - E_{Ga}^{bulk} < 0 \tag{14}$$

$$\Delta \mu_N = \mu_N - \frac{E_{N_2}^{mol}}{2} < 0 \tag{15}$$

Furthermore, the total energies of the elements and their ternary alloy in their ground states are related to the enthalpy of formation of Mn₃GaN by the formula:

$$-\Delta H^{f}_{Mn_{3}GaN} = E^{bulk}_{Mn_{3}GaN} - 3E^{bulk}_{Mn} - E^{bulk}_{Ga} - E^{mol}_{N_{2}}.$$
 (16)

with a computed value of $\Delta H_{Mn_3GaN}^f = -1.58$ eV. The lower boundary conditions are obtained combining equations (13), (14), (15) and the energy-chemical potential relationship:

$$E_{Mn_3GaN}^{bulk} = 3\mu_{Mn} + \mu_{Ga} + \mu_N \tag{17}$$

⁴⁸¹ resulting in the formula:

$$3\Delta\mu_{Mn} + \Delta\mu_{Ga} > \Delta H^f_{Mn_3GaN} \tag{18}$$

⁴⁸² Considering the previous equations, $\Delta \mu_{Mn}$ has the following limits: Mn-rich conditions ⁴⁸³ ($\Delta \mu_{Mn} = 0$) and Mn-poor conditions ($\Delta \mu_{Mn} = \Delta H^f_{Mn_3GaN}/3$). Similarly, the limits for ⁴⁸⁴ $\Delta \mu_{Ga}$ are: Ga-rich conditions ($\Delta \mu_{Ga}=0$) and Ga-poor conditions ($\Delta \mu_{Ga} = \Delta H^f_{Mn_3GaN}$).

485 5. Surface Formation Energy Plots

Therefore, we have calculated and plotted the surface formation energies of isolated 486 Mn₃GaN surfaces of the 4 models from Mn-poor to Mn-rich conditions, as well as from 487 Ga-poor to Ga-rich conditions (see Supplementary file for a plot of the surface formation 488 energies in 2-D). A top view of the isolated surfaces of each model is illustrated in Fig. 489 9(a-d). Figure. S3 depicts a side view of the atomic schemes for the isolated surfaces. As 490 seen in Fig. 9(e), model-1 (blue) and model-2 (mauve) are Mn₂N and MnN surface models 491 and are the least favorable configurations in all Mn and Ga chemical potentials. Model-3 492 (green) consists of a full Ga monolayer and is the most stable surface at Ga-rich conditions 493 including for the whole range of Mn chemical potential. However, since Ga-rich conditions 494 were not likely reached in the experiment, it suggests model-4 (red), consisting of a MnGa 495 monolayer, as the most likely observed surface structure. This configuration is the most 496 stable surface under Ga-poor conditions for both Mn-poor and Mn-rich conditions. 497

Interlayer distances	Mn-N	Mn-Ga
d_{1-2}	1.90	1.78
d_{2-3}	1.89	1.81
d_{3-4}	1.87	1.85
d_{4-5}	1.87	1.88
d_{5-6}	1.89	1.78
d_{6-7}	1.87	1.67

TABLE VI. Interlayer distances (Å) of different layers for Model-4.

We also investigated the structural properties of the $Mn_3GaN(001)$ surface of model-4. As seen in Fig. 8(e), two types of interlayer distances can be distinguished: one between Mn and N (Mn-N), and another between Mn and Ga (Mn-Ga). Table VI gives interlayer distances between consecutive layers going into the bulk. Although every interlayer distance is possible from this data, based upon the fact that the MnN-terminated surfaces are energetically unfavorable, we should expect to only find bi-layer (from 3.74 Å to 3.79 Å) step heights, in agreement with the STM step height profile measurement presented in Fig. 7(b).

505 I. Discussion

Although theory predicts a MnGa lowest energy surface, the AES measurements found 506 a N/Ga ratio of 1.72. This suggests possible disagreement with experiment. However, we 507 must first consider that the N:Ga flux ratio itself was set at 1.25:1, which itself could lead 508 to surface with excess nitrogen. Furthermore, as noted before, the amount of N present at 509 the surface might be affected by the precise sequence of shutdown of the N, Ga, and Mn 510 fluxes at the growth termination. Only a 1/2 second delay on closing the N source could 511 lead to an excess of 1.5-2.0 \times 10¹⁴ N atoms/cm² compared to one monolayer = 6.47 \times 512 10^{14} Ga/cm² (defined as 1 Ga/(3.932×10^{-8} cm)²), thus adding an additional 0.23 ML of 513 nitrogen. Together this could give easily 1/2 ML of excess N, potentially explaining the 514 measured AES N:Ga ratio (1.72 ± 0.26) . 515

516 IV. SUMMARY

We have presented experimental and theoretical results for the surface, film, and interface 517 properties of crystalline thin films consisting of Mn_3GaN epitaxially grown on cubic MgO 518 (001) substrates. RHEED shows that the film grows smoothly, consistent with *in-situ* STM 519 measurements which reveal atomically-smooth terraces separated by 2 ML height step edges, 520 consistent with bi-layer height steps. Careful analysis of the RHEED patterns show that after 521 only 25 min of growth, the lattice has evolved towards a close-to bulk value for Mn_3GaN but 522 retaining both *in-plane* and *out-of-plane* strain. Chemical stoichiometry measurements by 523 in-situ AES and ex-situ EDS (STEM) are consistent with a 3:1:1 compound ratio, and AES 524 ratios suggest a slightly N-rich surface, consistent with the growth conditions. Measurements 525 of the film lattice constants reveal a small amount of remnant strain originating most likely 526 from the lattice mismatch with the MgO substrate. The *in-plane* (transverse) strain ϵ_t is 527 determined to be +0.31 \pm 0.34 %, while the *out-of-plane* (longitudinal) strain ϵ_l is found to 528 be -1.22 \pm 0.13 %, corresponding to a derived lattice constant for a relaxed film of 3.922 \pm 529

⁵³⁰ 0.011 Å and a Poisson's ratio of 0.260 (theoretical value).

Non-collinear first-principles calculations were employed to investigate the structural 531 properties at the surface and interface. The adsorption study showed that all chemical 532 species (Mn, Ga, and N) prefer to bond with O atoms, making Ga and Mn adsorption fa-533 vorable. According to the surface and interface formation energies, Model-4 (MnGa) is the 534 most stable configuration under Mn-rich/Ga-poor conditions. Model-1 and Model-2 lose 535 stability due to unstable bonds between N and O, as presented in the adsorption study. 536 Model-3 (Ga layer) should become stable under Ga-rich conditions. Therefore, for the ex-537 perimental conditions shown in this work, the interface is expected to consist of MnGa/MgO 538 with a MnGa-terminated surface. We note that if the surface were consisting of a Mn_2N 539 final termination, we could expect a much larger N:Ga ratio in AES (since there would be 540 no Ga at the surface). Therefore, the AES result, although suggesting a slightly N-rich 541 surface is consistent with a stable MnGa surface termination. This study opens the door to 542 future more detailed investigations of the structural, magnetic, and electronic properties of 543 antiperovskite Mn₃GaN surfaces and thin films of interest for antiferromagnetic spintronics. 544

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555 DATA AVAILABILITY

The data supporting this study's findings are openly available in Zenodo at [Link will be added later].

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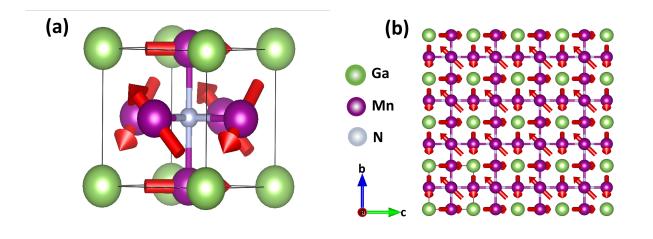


FIG. 1. (a) Schematic representation of cubic antiperovskite structure showing spin vectors in 3D perspective view; (b) view of atomic and spin structure along [001] showing 2 atomic layers.

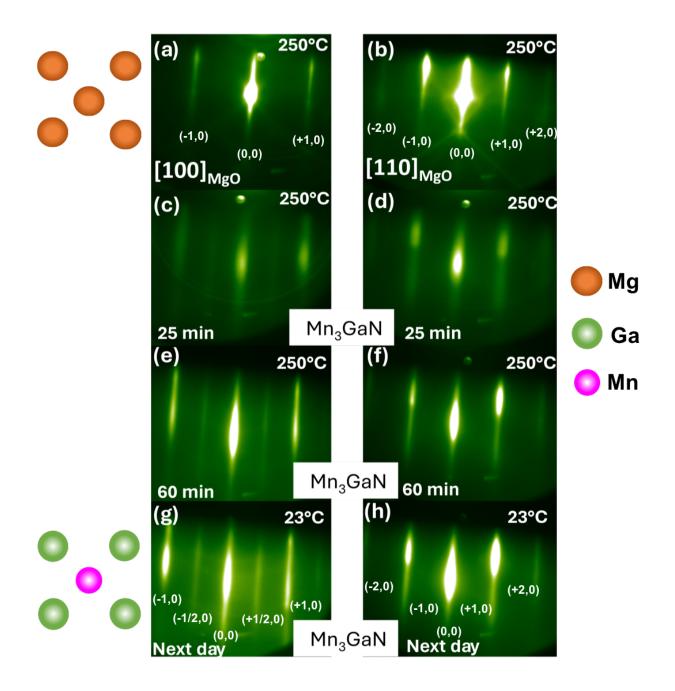


FIG. 2. Evolution of RHEED pattern during sample growth: (a) & (b) MgO substrate at 250 °C;
(c) & (d) Mn₃GaN after 25 minutes of growth; (e) & (f) Mn₃GaN after 60 minutes; (g) & (h) Mn₃GaN, next day at 23°C.

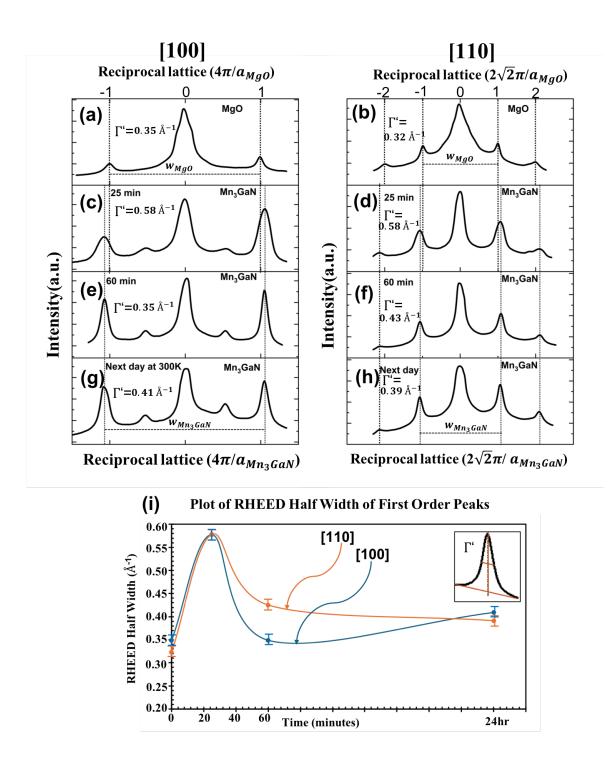


FIG. 3. Line profile of Mn₃GaN RHEED pattern in Fig. 2 along [100]_{MgO} and [110]_{MgO} directions:
(a) & (b) MgO substrate before growth; (c) & (d) Mn₃GaN line profile after 25 minutes of growth;
(e) & (f) Mn₃GaN line profile after 60 minutes; (g) & (h) Mn₃GaN line profile next day, at 23°C;
(i) RHEED Half Width of first order Mn₃GaN peaks along [100]_{MgO} and [110]_{MgO}.

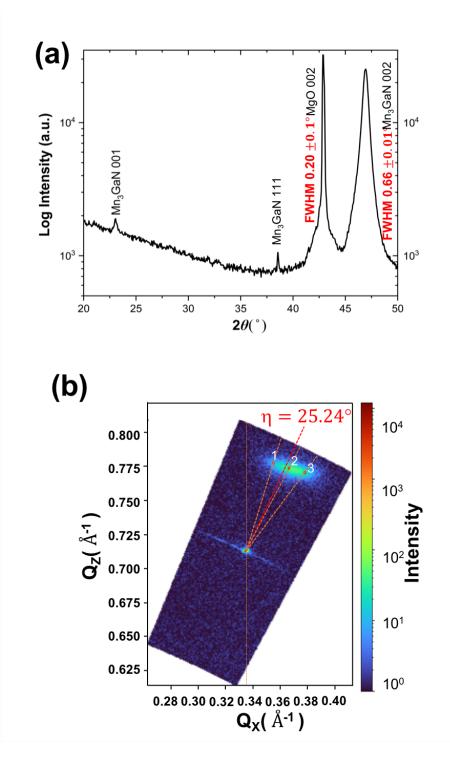


FIG. 4. (a) XRD pattern of Mn_3GaN (001) grown on MgO (001) substrate at 250 °C. The pattern reveals different peaks on the log scale. (b) Asymmetric (103) RSM scan of strain relaxed Mn_3GaN thin film.

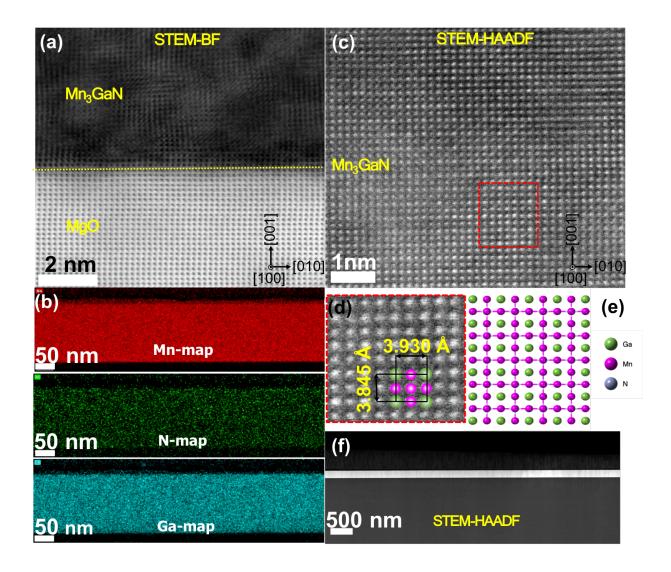


FIG. 5. (a) Bright-field image of the interface between MgO and grown Mn_3GaN ; (b) Elemental analysis showing the composition of Mn, N, and Ga for the sample; (c)(d) High-resolution lattice image of Mn_3GaN showing Mn and Ga atomic sites; (e) *a*-plane crystal model showing the Ga and Mn atoms with green and purple atoms; (f) 500 nm STEM-HAADF image showing flat and epitaxial film.

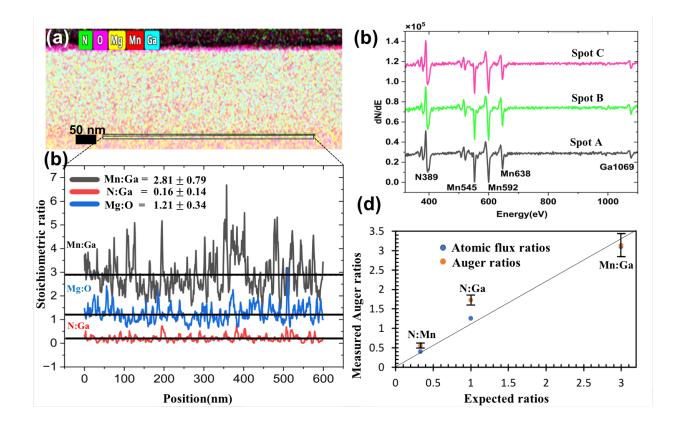


FIG. 6. (a) EDS elemental mapping of the grown Mn_3GaN film; (b) line profiles along the film/substrate interface in (a); (c) AES spectra showing the manganese, gallium, and nitrogen peaks of the Mn_3GaN sample. Spectra were taken at three different positions, as indicated by dark grey, light green, and magenta lines; (d) Graph showing measured auger ratios and atomic flux ratios of Mn:Ga, N:Ga and N:Mn.

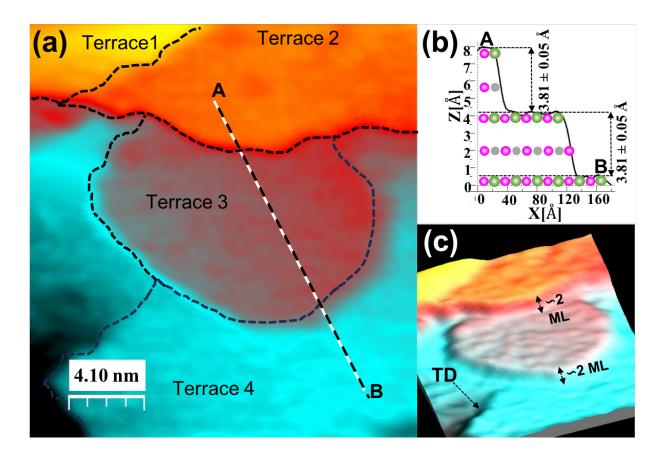


FIG. 7. STM image of Mn₃GaN grown on MgO(001). Scanning parameters; $V_{bias} = 1.50$ V and $I_s = 69$ pA. (a) 17.2 nm × 22.1 nm topographic (constant current) image showing multiple terraces. Terrace edges are highlighted by black dashed lines; (b) and (c) show the corresponding line profile along AB and a 3-dimensional perspective view of the topographic image shown in (a), respectively.

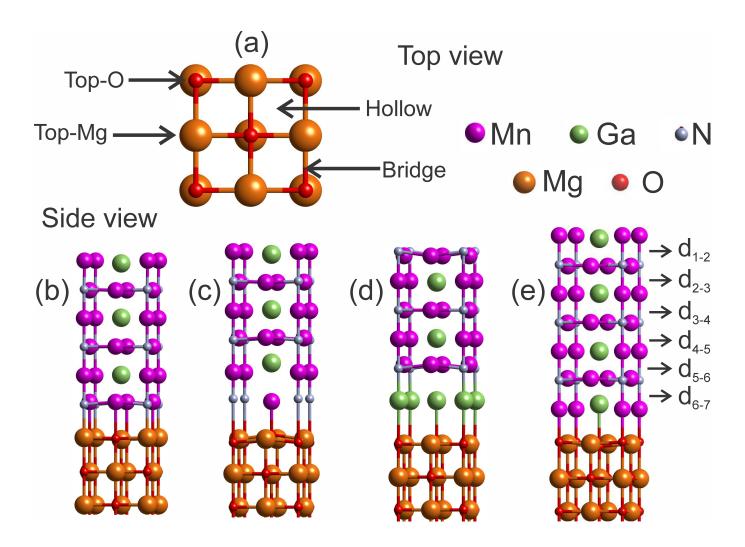


FIG. 8. (a) Top view of high symmetry sites for (001) MgO surface; (b-e) side views of the different interfaces models 1-4.

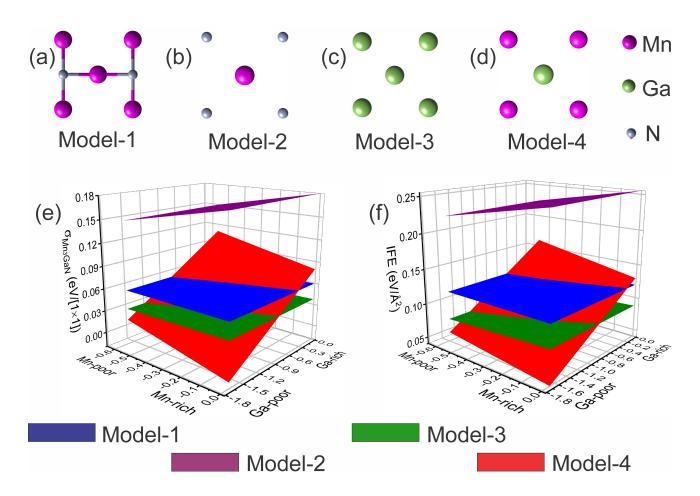


FIG. 9. (a)-(d) Top view of the isolated surfaces for models 1-4, respectively; (e) 3-D surface plot of the surface formation energies for the isolated surfaces of the four models; (f) 3-D surface plot of the interface formation energies for the different interface models.